IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hitoshi SAKAMOTO, et al.		TO, et al.	GAU:
SERIAL NO: NEW APPLICATION			EXAMINER:
FILED:	HEREWITH		
FOR:	HEXAGONAL BORON NITRIDE FILM WITH LOW DIELECTRIC CONSTANT, LAYER DIELECTRIC FILM AND METHOD OF PRODUCTION THEREOF, AND PLASMA CVD APPARATUS		
	REC	UEST FOR PRIORITY	Y
	IONER FOR PATENTS DRIA, VIRGINIA 22313		
SIR:			
	nefit of the filing date of U.S. Applicant to the provisions of 35 U.S.C. §12		32, filed June 15, 2001, pending, is claimed
☐ Full be §119(e			ned pursuant to the provisions of 35 U.S.C. ate Filed
	ants claim any right to priority from a visions of 35 U.S.C. §119, as noted b		o which they may be entitled pursuant to
In the matte	er of the above-identified application	for patent, notice is hereby given	ven that the applicants claim as priority:
COUNTR		CATION NUMBER	MONTH/DAY/YEAR
Japan Japan	2000-19 2001-0	· · · · ·	June 28, 2000 March 9, 2001
Japan Japan	2001-0		April 18, 2001
Certified co	opies of the corresponding Convention	n Application(s)	
□ are	submitted herewith		
□ will	be submitted prior to payment of the	Final Fee	
wer	e filed in prior application Serial No.	09/880,932 filed June 15, 20	01
Rec	e submitted to the International Bure eipt of the certified copies by the International Bure attack	ernational Bureau in a timely r	er manner under PCT Rule 17.1(a) has been
□ (A)	Application Serial No.(s) were filed	in prior application Serial No.	filed ; and
□ (B)	Application Serial No.(s)		
	are submitted herewith		
	l will be submitted prior to paymen	t of the Final Fee	
		Respec	etfully Submitted,
			N, SPIVAK, McCLELLAND, R & NEUSTADT, P.C.
		A	
_		Norma	n F. Oblon
Custome	Number	Registr	ration No. 24,618

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